



# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Application of:  
Nguyen, et al.

Serial No.: 10/672,420

Confirmation No.: Unknown

Filed: September 26, 2003

For: Interferometer Endpoint  
Monitoring Device

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Group Art Unit: Unknown

Examiner: Unknown

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>December 31, 2003</u> , with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.	
<u>December 31, 2003</u> Date	<u>Avi Hamud</u> Signature

Dear Sir:

## INFORMATION DISCLOSURE STATEMENT

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

While the information submitted in this Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/APPM/8349/AOP.

Respectfully submitted,

A handwritten signature in cursive script, reading "Ari Pramudji", written over a horizontal line.

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U.S. Department of Commerce, Patent and Trademark Office				Docket No.		Serial No.	
(PTO Form 1449 modified)				APPM/8349		10/672,420	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>				Applicant Nguyen, et al.		Confirmation No. Unknown	
(Use several sheets if necessary)				Filing Date		Group	
Examiner Unknown				September 26, 2003		Unknown	
<b>U.S. Patent Documents</b>							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A1	6,551,406	04/22/2003	Kilpi	118	728	12/27/2000
	A2	6,511,539	01/28/2003	Raaijmakers	117	102	09/08/1999
	A3	6,482,733	11/19/2002	Raaijmakers	438	633	04/26/2001
	A4	6,482,262	11/19/2002	Elers, Et Al.	117	84	10/13/2000
	A5	6,481,945	11/19/2002	Hasper, Et Al.	414	217	04/04/1999
	A6	6,478,872	11/12/2002	Chae, Et Al.	117	88	12/20/1999
	A7	6,475,910	11/05/2002	Sneh	438	685	09/22/2000
	A8	6,475,276	11/05/2002	Elers, Et Al.	117	84	10/13/2000
	A9	6,468,924	10/22/2002	Lee, Et Al.	438	763	05/31/2001
	A10	6,451,695	09/17/2002	Sneh	438	685	12/22/2000
	A11	6,451,119	09/17/2002	Sneh, Et Al.	118	715	11/29/2000
	A12	6,447,607	09/10/2002	Soininen, Et Al.	117	200	12/27/2000
	A13	6,428,859	08/06/2002	Chiang, Et Al.	427	457	03/19/2001
	A14	6,416,822	07/09/2002	Chiang, Et Al.	427	561	03/19/2001
	A15	6,416,577	07/09/2002	Suntola, Et Al.	117	88	12/09/1998
	A16	6,399,491	06/04/2002	Jeon, Et Al.	438	680	04/06/2001
	A17	6,391,785	05/21/2002	Satta, Et Al.	437	704	08/23/2000
	A18	6,379,748	04/30/2002	Bhandari, Et Al.	427	255.394	01/17/2000
	A19	6,372,598	04/16/2002	Kang, Et Al.	438	399	06/16/1999
	A20	6,358,829	03/19/2002	Yoon, Et Al.	438	597	09/16/1999
	A21	6,348,376	02/19/2002	Lim, Et Al.	438	253	01/19/2001
	A22	6,342,277	01/29/2002	Sherman	427	562	04/14/1999
	A23	6,306,216	10/23/2001	Kim, Et Al.	118	725	07/12/2000
	A24	6,305,314	10/23/2001	Sneh, Et Al.	118	723	12/17/1999
	A25	6,287,965	09/11/2001	Kang, Et Al.	438	648	02/23/2000
	A26	6,284,646	09/04/2001	Leem	438	629	08/19/1998
Examiner					Date Considered		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

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Examiner Unknown		September 26, 2003	Unknown

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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A27	6,270,572	08/07/2001	Kim, Et Al.	117	93	08/09/1999
	A28	6,231,672	05/15/2001	Choi, Et Al.	118	715	05/18/1999
	A29	6,207,487	03/27/2001	Kim, Et Al.	438	238	10/12/1999
	A30	6,203,613	03/20/2001	Gates, Et Al	117	104	10/19/1999
	A31	6,200,893	03/13/2001	Sneh	438	685	03/11/1999
	A32	6,197,683	03/06/2001	Kang, Et Al.	438	643	09/18/1998
	A33	6,183,563	02/06/2001	Choi, Et Al.	118	715	05/18/1999
	A34	6,174,809	01/16/2001	Kang, Et Al.	438	682	12/15/1998
	A35	6,174,377	01/16/2001	Doering, Et Al.	118	729	01/04/1999
	A36	6,144,060	11/07/2000	Park, Et Al.	257	310	07/31/1998
	A37	6,139,700	10/31/2000	Kang, Et Al.	204	192.17	09/30/1998
	A38	6,124,158	09/26/2000	Dautartas, Et Al.	438	216	06/08/1999
	A39	6,084,302	07/04/2000	Sandhu	257	751	12/26/1995
	A40	6,042,652	03/28/2000	Hyun, Et Al.	118	719	09/07/1999
	A41	6,015,917	01/18/2000	Bhandari, Et Al.	556	12	01/23/1998
	A42	6,015,590	01/18/2000	Suntola, Et Al.	427	255.23	11/28/1995
	A43	5,923,056	07/13/1999	Lee, Et Al.	257	192	03/12/1998
	A44	5,916,365	06/29/1999	Sherman	117	92	08/16/1996
	A45	5,879,459	03/09/1999	Gadgli, Et Al.	118	715	08/29/1997
	A46	5,866,795	02/02/1999	Wang, et al.	73	1.36	03/17/1997
	A47	5,855,680	01/05/1999	Soininen, Et Al.	118	719	11/28/1995
	A48	5,835,677	11/10/1998	Li, Et Al.	392	401	10/03/1996
	A49	5,807,792	09/15/1998	Ilg, Et Al.	438	758	12/18/1996
	A50	5,796,116	08/18/1998	Nakata, Et Al.	257	66	08/18/1998
	A51	5,711,811	01/27/1998	Suntola, Et Al.	118	711	10/02/1996
	A52	5,674,786	10/07/1998	Turner, Et Al.	437	225	06/05/1995

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Examiner Unknown		September 26, 2003	Unknown

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	A54	5,483,919	01/16/1996	Yokoyama, Et Al	117	89	08/17/1994
	A55	5,480,818	01/02/1996	Matsumoto, Et Al.	437	40	02/09/1993
	A56	5,443,647	08/22/1995	Aucoin, Et Al.	118	723	07/11/1994
	A57	5,441,703	08/15/1995	Jurgensen	422	129	03/29/1994
	A58	5,374,570	12/20/1994	Nasu, Et Al.	437	40	08/19/1993
	A59	5,360,738	11/01/1994	Jones, et al.	436	30	04/16/1993
	A60	5,294,286	03/15/1994	Nishizawa, Et Al.	156	610	01/12/1993
	A61	5,281,274	01/25/1994	Yoder	118	697	02/04/1993
	A62	5,225,366	07/06/1993	Yoder	437	108	06/22/1990
	A63	4,993,357	02/19/1991	Scholz	118	715	12/21/1989
	A64	4,834,831	05/30/1989	Nishizawa, Et Al	156	611	09/04/1987
	A65	4,413,022	11/1/1983	Suntola, Et Al.	427	255.2	06/21/1979
	A66	4,389,973	06/28/1983	Suntola, Et Al.	118	725	12/11/1981
	A67	4,058,430	11/15/1977	Suntola, Et Al.	156	611	11/25/1975
	A68	2002/0009544	01/24/2002	McFeely, et al.	427	248.1	08/20/1999
	A69	20020082296	06/27/2002	Verschoor, Et Al.	514	557	05/02/2001
	A70	20030075925	04/24/2003	Lindfors, Et Al.	285	367	06/28/2002
	A71	20030075273	04/24/2003	Kilpela, Et Al.	156	345.33	08/14/2002
	A72	20030072975	04/17/2003	Shero, Et Al.	428	704	09/26/2002
	A73	20030049942	03/13/2003	Haukka, Et Al.	438	778	08/22/2002
	A74	20030042630	03/06/2003	Babcoke, Et Al.	261	121.1	09/05/2001
	A75	20030031807	02/13/2003	Elers, Et Al.	427	569	09/17/2002
	A76	20030013320	01/16/2003	Kim, Et Al.	438	778	05/31/2001
	A77	20030004723	01/02/2003	Chihara	704	260	01/29/2002
	A78	20020197402	12/26/2002	Chiang, Et Al.	427	255.39	08/05/2002

Examiner

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<b>U.S. Patent Documents</b>							
*Examine r Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A79	20020187256	12/12/2002	Elers, Et Al.	427	99	07/30/2002
	A80	20020182320	12/05/2002	Leskela, Et Al.	427	250	03/15/2002
	A81	20020177282	11/28/2002	Song	438	300	12/18/2001
	A82	20020164423	11/17/2002	Chiang, Et Al.	427	255.28	05/03/2002
	A83	20020164421	11/07/2002	Chiang, Et Al.	427	248.1	05/03/2002
	A84	20020162506	11/07/2002	Sneh, Et Al.	118	715	06/28/2002
	A85	20020155722	10/24/2002	Satta, Et Al.	438	704	04/15/2002
	A86	20020146511	10/10/2002	Chiang, Et Al.	427	248.1	10/24/2001
	A87	20020144657	10/10/2002	Chiang, Et Al.	118	723 E	10/03/2001
	A88	20020144655	10/10/2002	Chiang, Et Al.	118	715	10/24/2001
	A89	20020134307	09/26/2002	Choi	118	715	11/30/2000
	A90	2002008570	08/15/2002	Lindfors	118	715	04/16/2001
	A91	20020106536	08/08/2002	Lee, Et Al.	428	702	02/02/2001
	A92	20020104481	08/08/2002	Chiang, Et Al.	118	723	03/19/2001
	A93	20020098627	07/25/2002	Pomarede, Et Al.	438	149	08/31/2001
	A94	20020094689	07/18/2002	Park	438	694	03/07/2002
	A95	20020092471	07/18/2002	Kang, Et Al.	118	715	01/16/2002
	A96	20020086106	07/04/2002	Park, Et Al.	427	248.1	11/07/2001
	A97	20020076837	06/20/2002	Hujanen, Et Al.	438	3	11/28/2001
	A98	20020076508	06/20/2002	Chiang, Et Al.	427	569	12/19/2001
	A99	20020076507	06/20/2002	Chiang, Et Al.	427	569	10/24/2001
	A100	20020076481	06/20/2002	Chiang, Et Al.	427	8	10/24/2001
	A101	20020073924	06/20/2002	Chiang, Et Al.	118	723 R	10/24/2001
	A102	20020068458	06/06/2002	Chiang, Et Al.	438	694	11/26/2001
	A103	20020066411	06/06/2002	Chiang, Et Al.	118	724	05/10/2001
	A104	20020052097	05/02/2002	Park	438	507	05/03/2001
Examiner					Date Considered		
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Examiner Unknown				September 26, 2003		Unknown	
<b>U.S. Patent Documents</b>							
*Examine r Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A105	20020048635	04/25/2002	Kim, Et Al.	427	331	10/08/1999
	A106	20020041931	04/11/2002	Suntola, Et Al.	427	255.28	05/14/2001
	A107	20020031618	03/14/2002	Sherman	427	569	10/09/2001
	A108	20020021544	02/21/2002	Cho, Et Al.	361	200	08/07/2001
	A109	20020020869	02/21/2002	Park, Et Al.	257	306	12/20/2000
	A110	20020007790	01/24/2002	Park	118	715	05/03/2001
	A111	20020000598	01/03/2002	Kang, Et Al.	257	301	07/26/2001
	A112	20020000196	01/03/2002	Park	118	715	05/03/2001
	A113	20010054769	12/27/2001	Raaijmakers, Et Al	257	758	04/26/2001
	A114	20010054730	12/27/2001	Kim, Et Al.	257	301	05/23/2001
	A115	20010054377	12/27/2001	Lindfors, Et Al.	117	104	04/16/2001
	A116	20010042799	11/22/2001	Kim, Et Al.	239	553	02/02/2001
	A117	20010042523	11/22/2001	Kesala	122	6.6	05/14/2001
	A118	20010041250	11/15/2001	Werkhoven, Et Al.	428	212	03/06/2001
	A119	20010034123	10/25/2001	Jeon, Et Al.	438	643	04/06/2001
	A120	20010028924	10/11/2001	Sherman	427	255.28	05/24/2001
	A121	20010025979	10/04/2001	Kim, Et Al.	257	315	12/04/2000
	A122	20010024387	09/27/2001	Raaijmakers, Et Al	365	200	02/22/2001
	A123	20010014371	08/16/2001	Kilpi	427	255.28	12/27/2000
	A124	20010013312	08/16/2001	Soininen, Et Al.	117	86	12/27/2000
	A125	20010011526	08/09/2001	Doering, Et Al.	118	729	01/16/2001
	A126	20010009695	07/26/2001	Saanila, Et Al.	427	255.39	01/18/2001
	A127	20010009140	07/26/2001	Bondestan, Et Al.	118	725	01/25/2001
	A128	20010002280	05/31/2001	Sneh	427	255.28	12/22/2000
	A129	20010000866	05/10/2001	Sneh, Et Al.	118	723	11/29/2000
	A130						
Examiner					Date Considered		
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**U.S. Patent Documents**

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	A131							
	A132							
	A133							
	A134							

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1	WO 02/45167	06/06/2002	WO	H01L	27/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B2	WO 02/43115	05/30/2002	WO	H01L		<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B3	WO 02/08488	01/31/2002	WO	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B4	WO 02/08485	01/31/2002	WO	C23C	16/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B5	WO 01/66832	09/13/2001	WO	C30B	25/14	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B6	WO 01/36702	05/25/2001	WO	C23C	16/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B7	WO 01/29893	04/26/2001	WO	H01L	21/768	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B8	WO 01/29891	04/26/2001	WO	H01L	21/768	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B9	WO 01/29280	04/26/2001	WO	C23C	16/32	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B10	WO 01/27347	04/19/2001	WO	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B11	WO 01/27346	04/19/2001	WO	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B12	WO 01/17692	03/15/2001	WO	B05C	11/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B13	WO 01/15220	03/01/2001	WO	H01L	21/768	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B14	WO 00/79576	12/28/2000	WO	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B15	WO 00/54320	09/14/2000	WO	H01L	21/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B16	WO 00/16377	03/23/2000	WO	H01L		<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B17	WO 99/65064	12/16/1999	WO	H01L	21/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B18	WO 99/29924	06/17/1999	WO	C23C	16/04	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B19	WO 99/01595	01/14/1999	WO	C30B	25/14	<input type="checkbox"/>	<input checked="" type="checkbox"/>

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(Use several sheets if necessary)		Filing Date September 26, 2003	Group Unknown
Examiner      Unknown			

**For Ign Patent Documents**

*Examine r Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B20	WO 96/17107	06/06/1996	WO	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B21	58098917	06/10/1983	JP	H03J	7/02	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B22	2001172767 (w/ English Abstract)	06/26/2001	JP	C23C	16/40	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B23	2001111000	04/20/2001	JP	H01L	27/105	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B24	2001020075 (Abstract Only)	11/15/2000	JP	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B25	2000319772 (Abstract Only)	03/28/2000	JP	C23C	16/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B26	6224138 (Abstract Only)	05/31/1994	JP	C30B	25/14	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B27	5270997 (Abstract Only)	10/19/1993	JP	C30B	29/68	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B28	5234899 (Abstract Only)	09/10/1993	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B29	5206036 (Abstract Only)	08/13/1993	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B30	5047666 (Abstract Only)	02/26/1993	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B31	4291916 (Abstract Only)	09/23/1992	JP	C30B	25/10B	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B32	1 167 569	01/02/2002	EP	C23C	16/455	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B33	2 355 727	05/02/2001	GB	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>

**OTHER ART**

*Examine r Initial		Including Author, Title, Date, Pertinent Pages, Etc.
	C1	J.P. Stagg, J. Christer, E. J. Thrush and J. Crawley, "Measurement and Control of Reagent Concentrations in MOCVD Reactor Using Ultrasonics," Journal of Crystal Growth 120(1992) Pages 98-102
	C2	"MultiGas™ 2030," MKS Instruments, Inc., Bulletin 2030-04/02
Examiner		Date Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office		Docket No.	Serial No.
(PTO Form 1449 modified)		APPM/8349	10/672,420
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>		Applicant Nguyen, et al.	Confirmation No. Unknown
(Use several sheets if necessary)		Filing Date	Group
Examiner Unknown		September 26, 2003	Unknown
<b>OTHER ART</b>			
*Examine r Initial		Including Author, Title, Date, Pertinent Pages, Etc.	
	C3	Kukli, <i>et al.</i> , "Tailoring the Dielectric Properties of HfO <sub>2</sub> -Ta <sub>2</sub> O <sub>5</sub> Nanolaminates," Applied Physics Letters, Vol. 68, No. 26, June 24, 1996; p. 3737-9	
	C4	Kukli, <i>et al.</i> "Atomic Layer Epitaxy Growth of Tantalum Oxide Thin Films from Ta(OC <sub>2</sub> H <sub>5</sub> ) <sub>5</sub> and H <sub>2</sub> O," Journal of the Electrochemical Society, Vol. 142, No. 5, May 1995; p. 1670-5	
	C5	Kukli, <i>et al.</i> , "In situ Study of Atomic Layer Epitaxy Growth of Tantalum Oxide Thin Films From Ta(OC <sub>2</sub> H <sub>5</sub> ) <sub>5</sub> and H <sub>2</sub> O," Applied Surface Science, Vol. 112, March 1997, p. 236-42	
	C6	Kukli, <i>et al.</i> , "Properties of Ta <sub>2</sub> O <sub>5</sub> -Based Dielectric Nanolaminates Deposited by Atomic Layer Epitaxy," Journal of the Electrochemical Society, Vol. 144, No. 1, Jan. 1997; p. 300-6	
	C7	Kukli, <i>et al.</i> , "Properties of {Nb <sub>1-x</sub> Ta <sub>x</sub> } <sub>2</sub> O <sub>5</sub> Solid Solutions and {Nb <sub>1-x</sub> Ta <sub>x</sub> } <sub>2</sub> O <sub>5</sub> -ZrO <sub>2</sub> Nanolaminates Grown by Atomic Layer Epitaxy," 1997; p. 785-93	
	C8	Ritala, M., <i>et al.</i> , "Chemical Vapor Deposition," January 1999, p. 6-9	
	C9	Rossnagel, <i>et al.</i> "Plasma-enhanced Atomic Layer Deposition of Ta and Ti for Interconnect Diffusion Barriers," J. Vac. Sci. Technol. B., Vol. 18, No. 4 (July 2000); p2016-20	
	C10	Niinisto, <i>et al.</i> "Synthesis of Oxide Thin Films and Overlayers by Atomic Layer Epitaxy for Advanced Applications," Materials Science and Engineering B41 (1996) 23-29	
	C11	Eisenbraum, <i>et al.</i> "Atomic Layer Deposition (ALD) of Tantalum-based materials for zero thickness copper barrier applications," Proceedings of the IEEE 2001 International Interconnect Technology Conference (Cat. No. 01EX461) 2001	
	C12	Clark-Phelps, <i>et al.</i> "Engineered Tantalum Aluminate and Hafnium Aluminate ALD Films for Ultrathin Dielectric Films with Improved Electrical and Thermal Properties," Mat. Res. Soc. Symp. Proc. Vol. 670 (2001)	
	C13		
	C14		
	C15		
Examiner		Date Considered	
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